

Abstract

It is an object of the present invention to provide a corrosion resistant thermal type mass flow rate sensor and a fluid supply device for which the sensor is employed, thus allowing to enhance corrosion resistance of the thermal type mass flow rate sensor, improve responsiveness, achieve to be particle-free, and prevent unevenness of product qualities.

Concretely, a thermal type mass flow rate sensor is constituted with a sensor part 1 comprising a corrosion resistant metal substrate 2 formed to be a thin plate by applying electrolytic etching on the rear face side of a corrosion resistant metal material W and a thin film F to form a temperature sensor 3 and a heater 4 mounted on the rear face side of the said corrosion resistant metal substrate 2, and a sensor base 13 hermetically fitted by welding to the outer periphery of the corrosion resistant metal substrate 2 of the afore-mentioned sensor part 1 fitted into a fixture groove 13a.